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A. Kerber, GLOBALFOUNDRIES Inc.

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B. Kaczer, J. Franco, M. Cho, T. Grasser, P. Roussel, S. Tyaginov*, M. Bina*, Y. Wimmer*, L.-M. Procel**, L. Trojman**, F. Crupi***, G. Pitner^, V. Putcha, P. Weckx, E. Bury, Z. Ji^, A. De Keersgieter, T. Chiarella, N. Horiguchi, G. Groeseneken and A. Thean, imec, *TU Wien, **USFQ, ***University of Calabria, ^visiting imec from Stanford University, ^^visiting imec from Liverpool John Moores University*

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P. Jain, S.S. Sapatnekar and J. Cortadella**, Qualcomm Technologies Inc., *University of Minnesota, **Universitat Politècnica de Catalunya*

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J. Poortmans, E. Voroshaszi, W. Deceuninck and J. Szlufcik, imec, *University Hasselt*

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M. Barbato, M. Meneghini, A. Cester, A. Barbato, E. Zanoni, G. Meneghesso, G. Mura, D. Tonini**, A. Voltan** and G. Cellere**, University of Padova, *University of Cagliari, **Applied Materials Italia S.r.l.*

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M. Anders, P. Lenahan and A. Lelis, Penn State University, *US Army Research Laboratory*

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M. Si, S. Shin, N. Conrad, J. Gu, J. Zhang, A. Alam and P. Ye, Purdue University

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*N. Goel, T. Naphade and S. Mahapatra, Indian Institute of Technology Bombay
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M. Wang, Z. Liu, T. Yamashita, J. Stathis and C.-y. Chen*, IBM @ Albany Nanotech, *IBM Research Division, T.J. Watson Research Center*

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N. Goel, P. Dubey, J. Kawa** and S. Mahapatra, IIT Bombay, *Synopsys India Pvt. Ltd., **Synopsys, Inc.*

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T.-C. Kao, J.-H. Lee, C.-H. Lien, C.-H. Wang**, K.-C. Tai** and H.-D. Su*, National Tsing Hua University, *GlobalFoundries, Inc, Richtek Technology Corporation*

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A. Yassine, L. Blair and W. Seifert, Advanced Micro Devices, Inc.

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T.-Y. Yew, Y.-C. Huang, M.-H. Hsieh, W. Wang, R. Hsieh, Y.-H. Lee and K. Wu, Taiwan Semiconductor Manufacturing Company

GD-3 Extended TDDB Power-law Validation for High-Voltage Applications Such as OTP Memories in High-k CMOS 28nm FDSOI Technology

*A. Benoist, S. Denorme, X. Federspiel, B. Allard and P. Candelier, Université de Lyon, *STMicroelectronics*

Interconnect Metallization Reliability

IT-1 Exploration of Electromigration and Joule Heating Effect Associated with Un-silicided N+ Poly

X.-F. Zhao, A. Zhao, V. Chang, J. Wu, M. Li, M. Zhang and W.-T. Kary Chien, Semiconductor Manufacturing International Corp.

IT-2 Interconnect Design Study for Electromigration Reliability Improvement

*G. Marti, L. Arnaud**, D. Ney and Y. Wouters*, STMicroelectronics, *SIMaP, **CEA-Leti Minatec*

IT-3 Wafer-level Electromigration for Reliability Monitoring: Quick-turn Electromigration Stress with Correlation to Package-level Stress

D. Slottke, R.J. Kamaladasa, M. Harmes, I. Tsameret, M. Kobrinsky, T. McMullen and J. Dunklee**, Intel Corporation, *Cascade Microtech Inc., **Celadon Systems Inc.*

Memory

MY-1 Analysis of SET and RESET States Drift of Phase-Change Memories by Low Frequency Noise Measurements

S. Souiki-Figuigui, V. Sousa, G. Ghibaudo, G. Navarro, M. Coue, L. Perniola, P. Zuliani** and R. Annunziata**, CEA/LETI, *IMEP-LAHC, **STMicroelectronics*

MY-2 A Collective Relaxation Model for Resistance Drift in Phase Change Memory Cells

A. Sebastian, D. Krebs, M. Le Gallo, H. Pozidis and E. Eleftheriou, IBM Research - Zurich

MY-3 Investigation of the Data Retention Mechanism and Modeling for the High Reliability Embedded Split-Gate MONOS Flash Memory

Y. Kawashima, T. Hashimoto and I. Yamakawa, Renesas Electronics Corporation, *Hitachi, Ltd.*

MY-4 Data Retention Statistics and Modelling in HfO₂ Resistive Switching Memories

S. Ambrogio, S. Balatti, Z.-Q. Wang, Y.-S. Chen, H.-Y. Lee*, F.T. Chen and D. Ielmini, Politecnico di Milano, *Industrial Technology Research Institute (ITRI)*

MY-5 RTS Noise Reduction of 1Y-nm Floating Gate NAND Flash Memory Using Process Optimization

S. Kim, M. Lee, G.-B. Choi, J. Lee, Y. Lee, M. Cho, K.-O. Ahn and J. Kim, SK Hynix Inc.

MY-6 Cycling Pattern and Read/Bake Conditions Dependence of Random Telegraph Noise in Decanometer NAND Flash Arrays

C. Miccoli, G.M. Paolucci, C. Monzio Compagnoni*, A.S. Spinelli* and A. Goda, Micron Technology Inc., *Politecnico di Milano*

MY-7 Conductive Filaments Multiplicity as a Variability Factor in CBRAM

U. Celano, L. Goux, A. Belmonte, K. Opsomer, C. Detavernier, M. Jurczak and W. Vandervorst, imec, *University of Gent*

MY-8 Improvement of Oxide Reliability in NAND Flash Memories Using Tight Endurance Cycling with Shorter Idling Period

R. Shirota, B.-J. Yang, Y.-Y. Chiu, Y.-T. Wu, P.-Y. Wang, J.-H. Chang*, M. Yano*, M. Aoki*, T. Takeshita*, C.-Y. Wang* and I. Kurachi**, National Chiao-Tung University, *Winbond Electronics Corporation, **High Energy Accelerator Research Organization*

MY-9 SRAM Stability Design Comprehending 14nm FinFET Reliability

C. Bae, S. Pae, C.-s. Yu, K. Kim, Y. Kim and J. Park, Samsung Electronics

MY-11 Oxygen Vacancy Traps in Hi-K/Metal Gate Technologies and Their Potential for Embedded Memory Applications

C. Kothandaraman, X. Chen, D. Moy, D. Lea, S. Rosenblatt, F. Khan, D. Leu, T. Kirihata, D. Ioannou, G. LaRosa, J. Johnson, N. Robson and S. Iyer, IBM Microelectronics

MY-12 Impact of Nanoscale Polarization Relaxation on Endurance Reliability of One-Transistor Hybrid Memory Using Combined Storage Mechanisms

Y.-C. Chiu, C.-Y. Chang, H.-H. Hsu C.-H. Cheng and M.-H. Lee*, National Chiao-Tung University, National Taiwan Normal University*

MY-13 Four Point Probe Ramped Voltage Stress as an Efficient Method to Understand down of STT-MRAM MgO Tunnel Junctions

S. Van Beek, K. Martens*, P. Roussel, G. Donadio, J. Swerts, S. Mertens, G. Kar, T. Min and G. Groeseneken*, Imec, *KU Leuven*

Process Integration

PI-1 An Investigation of Process Dependence of Porous IMD TDDB

W.Y. Zhang, M.C. Silvestre, A. Selvam, E. Ramanathan, C. Ordonio, J. Schaller, T. Shen, K.B. Yeap, C. Capasso, P. Justison and J.H. Lee, GLOBALFOUNDRIES Inc.

PI-2 New Insight in Plasma Charging Impact on Gate Oxide down in FDSOI Technology

M. Akbal, G. Ribes and L. Vallier, STMicroelectronics, *LTM/CNRS*

PI-3 Reliability of HfAlO_x in Multi Layered Gate Stack

M.N. Bhuyian and D. Misra, New Jersey Institute of Technology

Product IC Reliability

PR-1 A Failure Physics Model for Hardware Trojan Detection Based on Frequency Spectrum Analysis

C. He, B. Hou, L. Wang, Y. En and S. Xie, No.5 Electronics Research Institute of the Ministry of Industry and Information Technology

PR-2 Printed Circuit Board (PCB) Charge Induced Product Yield-Loss During the Final Test

J.-H. Lee, K. Takahashi, M. Prabhu and M.I. Natarajan, GLOBALFOUNDRIES Inc.

Soft Error

SE-1 Investigation of Single Event Upset and Total Ionizing Dose in FeRAM for Medical Electronic Tag

T. Uemura and M. Hashimoto, Osaka University

SE-2 Soft Error Immune Latch Design for 20 nm Bulk CMOS

T. Uemura, T. Kato, H. Matsuyama and M. Hashimoto, Fujitsu Semiconductor, *Osaka University*

SE-3 Techniques for Heavy Ion Microbeam Analysis of FPGA SER Sensitivity

A. Evans, D. Alexandrescu, V. Ferlet-Cavrois and K.-V. Obbe**, IROC Technologies, *ESA/ESTEC, **GSI*

SE-4 Analysis of Advanced Circuits for SET Measurement

R. Liu, A. Evans, Q. Wu, Y. Li, L. Chen, S.-J. Wen**, R. Wong** and R. Fung**, University of Saskatchewan, *IROC Technologies, **Cisco Systems*

SE-6 Impact of Package on Neutron Induced Single Event Upset in 20 nm SRAM

T. Uemura, T. Kato, H. Matsuyama and M. Hashimoto, Fujitsu Semiconductor, *Osaka University*

SE-7 Alpha Soft Error Rate of FDSOI 28 nm SRAMs: Experimental Testing and Simulation Analysis
V. Malherbe, G. Gasiot, D. Soussan, A. Patris, J.-L. Autran* and P. Roche, STMicroelectronics, *Aix-Marseille University & CNRS, IM2NP*

SE-9 Frequency and Voltage Effects on SER on a 65nm Sparc-V8 Microprocessor Under Radiation Test
C. Bottoni, B. Coeffic, J.-M. Daveau, G. Gasiot, F. Abouzeid, S. Clerc, L. Naviner and P. Roche, STMicroelectronics, *Telecom ParisTech*

SE-11 MBU-Calc: A Compact Model for Multi-Bit Upset (MBU) SER Estimation
W. Wu and N. Seifert, Intel Labs

SE-12 Logic Soft Error Study with 800-MHz DDR3 SDRAMs in 3x nm Using Proton and Neutron Beams
G.Y. Bak, S. Lee, H. Lee, K. Park, S. Baeg, S.J. Wen, R. Wong* and C. Slayman*, Hanyang University, *Cisco Systems Inc.*

Transistors

XT-1 New LFN and RTN Analysis Methodology in 28 and 14nm FD-SOI MOSFETs
C. Theodorou, E. Ioannidis, S. Haendler, N. Planes*, E. Josse*, C. Dimitriadis** and G. Ghibaudo, IMEP-LAHC, MINATEC, *STMicroelectronics, **Aristotle University of Thessaloniki*

XT-2 Hot-Carrier Degradation in Single-Layer Double-Gated Graphene Field-Effect Transistors
Y. Illarionov, M. Waltl, A. Smith, S. Vaziri*, M. Ostling*, T. Mueller, M. Lemme** and T. Grasser, TU Wien, *KTH Royal Institute, **University of Siegen*

XT-4 Impact of DC and RF Non-Conducting Stress on nMOS Reliability
A. Cattaneo, S. Pinarello, J.-E. Mueller and R. Weigel, Intel Mobile Communications, *University of Erlangen-Nuremberg*

XT-5 Investigation of Nitrogen Enhanced NBTI Effect Using the Universal Prediction Model
P. Wu, C. Ma**, L. Zhang, X. Lin* and M. Chan, The Hong Kong University of Science and Technology, * Peking University*

XT-6 Comprehensive Understanding of Hot Carrier Degradation in Multiple-fin SOI FinFETs
*H. Jiang, L. Yin, Y. Li, N. Xu**, K. Zhao*, Y. He, G. Du, X. Liu and X. Zhang, Peking University, *Beijing Information Science and Technology University, **University of California at Berkeley*

XT-7 PBTI and HCI Degradations of Ultrathin Body InGaAs-on-Insulator nMOSFETs Fabricated by Wafer Bonding
X. Tang, J. Lu, R. Zhang, Y. Zhao, W. Wu, C. Liu*, Y. Shi*, Z. Huang** and Y. Kong**, Zhejiang University, *Nanjing University, **Nanjing Electronic Devices Institute*

Session 5A - Gate Dielectrics Reliability

5A.1 General Features of Progressive down in Gate Oxides: A Compact Model (Invited)
F. Palumbo, M. Eizenberg and S. Lombardo, Technion, *CNR-IMM*

5A.2 Spectroscopy of SILC Trap Locations and Spatial Correlation Study of Percolation Path in the High-K and Interfacial Layer
N. Raghavan, M. Bosman and K.L. Pey, Singapore University of Technology and Design (SUTD), *A*STAR*

5A.3 On the Volatility of Oxide Defects: Activation, Deactivation, and Transformation
T. Grasser, M. Waltl, W. Goes, Y. Wimmer, A.-M. El-Sayed, A.L. Shluger* and B. Kaczer**, TU Wien, *UCL, **imec*

5A.5 Physical Understanding of Low Frequency Degradation of NMOS TDDB In High-K Metal Gate Stack-Based Technology. Implication on Lifetime Assessment
A. Bezza, M. Rafik, D. Roy, X. Federspiel, P. Mora, C. Diouf, V. Huard and G. Ghibaudo, STMicroelectronics, *IMEP-LAHC*

5A.6 A New TDDB Lifetime Model for AC Inverter-like Stress in Advance FinFET Structure
I.K. Chen, C.L. Chen, Y.-H. Lee, R. Lu, Y.W. Lee, H.H. Hsu, Y.W. Tseng, Y.W. Lin and J.R. Shih, TSMC.

5A.7 The Relationship Between Border Traps Characterized By AC Admittance and BTI in III-V MOS Devices

A. Vais, K. Martens, J. Franco, D. Lin, A. Alian, P. Roussel, S. Sioncke, N. Collaert, A. Thean, M. Heyns, G. Groeseneken and K. DeMeyer, imec

Session 5B – Memory

5B.1 Scaling and Write Error Rate of Perpendicular Spin Torque MRAM (Invited)

D. Worledge, IBM Research

5B.3 Understanding Pulsed-cycling Variability and Endurance in HfO_x RRAM

S. Balatti, S. Ambrogio, Z. Wang, S. Sills, A. Calderoni*, N. Ramaswamy* and D. Ielmini, Politecnico di Milano and IU.NET, *Micron Technology Inc.*

5B.4 A New Prediction Method for ReRAM Data Retention Statistics Based on 3D Filament Structures

Z. Wei, K. Katayama, S. Muraoka, R. Yasuhara, T. Mikawa and K. Eriguchi, Panasonic Corporation, *Kyoto University*

5B.5 A Microscopic Physical Description of RTN Current Fluctuations in HfO_x RRAM

F.M. Puglisi, P. Pavan, L. Vandelli, A. Padovani, M. Bertocchi and L. Larcher, Università di Modena e Reggio Emilia

5B.2 Monte Carlo Model of Reset Stochastics and Failure Rate Estimation of Read Disturb Mechanism in HfO_x RRAM

N. Raghavan, D. Frey, M. Bosman** and K.L. Pey, Singapore University of Technology and Design (SUTD), *Massachusetts Institute of Technology (MIT), **A*STAR Institute of Materials Research and Engineering (IMRE)*

5B.6 Phase-Change Memory: Feasibility of Reliable Multilevel-cell Storage and Retention at Elevated Temperatures

M. Stanisavljevic, A. Athmanathan, N. Papandreou, H. Pozidis and E. Eleftheriou, IBM Research – Zurich

5B.7 Impact of P/E Cycling on Read Current Fluctuation of NOR Flash Memory Cell: A Microscopic Perspective Based on Low Frequency Noise Analysis

X. Yang, J. Liu, Z. Zheng, Y. Wang, D. Jiang, S. Chiu, H. Wu* and M. Liu, Chinese Academy of Sciences, *Semiconductor Manufacturing International Corporation (SMIC)*

Session 5C - Chip Packaging Reliability

5C.1 Probabilistic Design for Reliability in Electronics and Photonics: Role, Significance, Attributes, Challenges (Invited)

E. Suhir, A. Bensoussan, G. Khatibi** and J. Nicolics**, Portland State University, *Institute of Technological Research (IRT), **Technical University*

5C.2 The Electromigration Behavior of Copper Pillars for Different Current Directions and Pillar Shapes

C. Hau-Riege, Y.W. Yau, K. Caffey, R. Kumar, Y.Y. Sun, A. Bao, M. Shah, L. Zhao, O. Bchir, A. Syed and S. Bezuk, Qualcomm Inc.

5C.3 Scenario for Catastrophic Failure in Interconnect Structure under Chip Package Interaction

M. Omiya, S. Kamiya, N. Shishido*, K. Koiwa*, H. Sato*, M. Nishida*, T. Suzuki**, T. Nakamura**, T. Suzuki*** and T. Nokuo***, Keio University, *Nagoya Institute of Technology, **Fujitsu Laboratories Ltd., ***JEOL, Ltd.*

5C.4 Semi-Empirical Stress-based Acceleration of Temperature Cycling Failure

D. Huitink and A. Lucero, Intel Corporation

5C.5 CPI Reliability and EMI Benefit for MIM CAP Embedded C4 Package

H. Chun, I.H. Baick, S.-S. Ha, E. Kwon, S. Lee, S. Kim, S. Pae and J. Park, Samsung Electronics

5C.6 Package Induced Stress Impact on Transistor Performance for Ultra-thin SoC

M. Kabir, D. Young, B. Kilic, I. Sauciuc, C. Sapp and G. Leatherman, Intel Corporation

Session 6A - Circuit Aging/Circuit Reliability

6A.1 Non-volatile Memory as Hardware Synapse in Neuromorphic Computing: A First Look at Reliability Issues

(Invited)

R. Shelby, G. Burr, I. Boybat and C. di Nolfo, IBM Almaden Research Center

6A.2 Long-term Data for BTI Degradation in 32nm IBM Microprocessor using HKMG Technology

P.-F. Lu, K. Jenkins, K. Paul Muller and R. Schaufler*, IBM Research, Thomas J. Watson Center, *IBM System and Technology Group*

6A.3 A Revolving Reference Odometer Circuit for BTI-Induced Frequency Fluctuation Measurements under Fast DVFS Transients

S. Satapathy, W.H. Choi, X. Wang and C.H. Kim, University of Minnesota, *Intel Corporation*

6A.4 The Impact and Implication of BTI/HCI Decoupling on Ring Oscillator

M.-H. Hsieh, Y.-C. Huang, T.-Y. Yew, W. Wang and Y.-H. Lee, Taiwan Semiconductor Manufacturing Company

6A.5 Assessing Intrinsic and Extrinsic End-of-Life Risk Using Functional SRAM Wafer Level Testing

Y.M. Randriamihaja, W. McMahon, S. Balasubramanian, T. Nigam, B. Parameshwaran, R. Mann, T. Klick, T. Schaefer, A. Kumar, Y. Song, V. Joshi, R. Ranjan and F. Chen, GLOBALFOUNDRIES, *Purdue University*

6A.6 SRAM Vmax Stability Considerations

D. Burnett, S. Balasubramanian, V. Joshi, S. Parihar, J. Higman and C. Weintraub, GLOBALFOUNDRIES Inc

Session 6B - Product IC Reliability

6B.1 28nm UTBB FDSOI Product Reliability/ Performance Trade-off Optimization Through Body bias Operation

P. Mora, X. Federspiel, F. Cacho, V. Huard and W. Arfaoui, STMicroelectronics

6B.2 Product-Level Reliability Estimator with Budget-Based Reliability Management in 20nm Technology

J.-G. Ahn, M.F. Lu, N. Navale, D. Graves, P.-C. Yeh, J. Chang and S.Y. Pai, Xilinx, Inc.

6B.3 From BTI Variability to Product Failure Rate: A Technology Scaling Perspective

V. Huard, D. Angot and F. Cacho, STMicroelectronics

6B.4 Analyzing Path Delays for Accelerated Testing of Logic Chips

E. Ray, B. Linder, R. Robertazzi, K. Stawiasz, A. Weger, E. Yashchin, J. Stathis and P. Song, IBM Thomas J. Watson Research Center

6B.5 CpK Approach for the Qualification of ECC-Designs with Single Bit Failures

G. Tempel, Infineon Technologies Dresden GmbH

Session 6C - Compound/Optoelectronics

6C.1 Commercialization and Reliability of 600V GaN Power Switches (Invited)

T. Kikkawa, T. Hosoda, K. Shono, K. Imanishi, Y. Asai, Y. Wu, L. Shen*, K. Smith*, D. Dunn*, S. Chowdhury*, P. Smith*, J. Gritters*, L. McCarthy*, R. Barr*, R. Lal*, U. Mishra* and P. Parikh, Transphorm Japan, Inc. *Trrransphorm, Inc.*

6C.2 Thermal Activation of PBTI-related Stress and Recovery Processes in GaN MIS-HEMTs using on-wafer Heaters

P. Lager, S. Donsa, P. Spreitzer, G. Pobegen, M. Reiner, H. Naharashi, J. Mohamed, H. Mösslacher, G. Prechtel, D. Pogany** and C. Ostermaier, Infineon Technologies Austria AG, *Kompetenzzentrum für Automobil- und Industrieelektronik, **Vienna University of Technology*

6C.3 Origin of Physical Degradation in AlGaIn/GaN on Si High Electron Mobility Transistors under Reverse bias Stressing

W.A. Sasangka, G.J. Syaranamual, C.L. Gan and C.V. Thompson, Singapore-MIT Alliance for Research and Technology

6C.4 Time Dependent Dielectric down (TDDb) Evaluation of PE-ALD SiN Gate Dielectrics on AlGaIn/GaN Recessed Gate D-mode MIS-HEMTs and E-mode MIS-FETs

T.-L. Wu, D. Marcon, B. De Jaeger, M. Van Hove, B. Bakeroot, S. Stoffels, G. Groeseneken, S. Decoutere and R. Roelofs, imec, *ASM*

6C.5 Positive-Bias Temperature Instability (PBTI) of GaN MOSFETs

A. Guo and J. del Alamo, Massachusetts Institute of Technology

6C.6 Instabilities of SiC MOSFETs During use Conditions and Following bias Temperature Stress

G. Pobegen and A. Krassnig, Kompetenzzentrum für Automobil- und Industrieelektronik (KAI) BmbH